

MACROVUE-P SCANNING ACOUSTIC MICROSCOPE

Semiconductor Package Failure Analysis
voids · disbonds · cracks · delamination · internal defects

Customer Interface

Dual 22" HD LED Monitors

Fixtures

Tray Fixture
Optional Through
Transmission Bracket
LED illumination

Instrumentation

Digital Pulser Receiver
Optional second channel
Up to 12 GHz Digitizer

Scan Area

Up to 1000 mm x 800 mm

Maintenance Free Scan Axis

Motor: Quad Linear Servo
Max Velocity: Up to 2000 mm/s
Accuracy & Repeatability: +/- 0.5 micron

Scan Envelope:

Up to 1000 mm

Low Maintenance Step Axis:

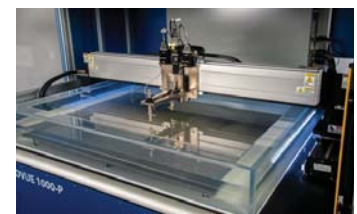
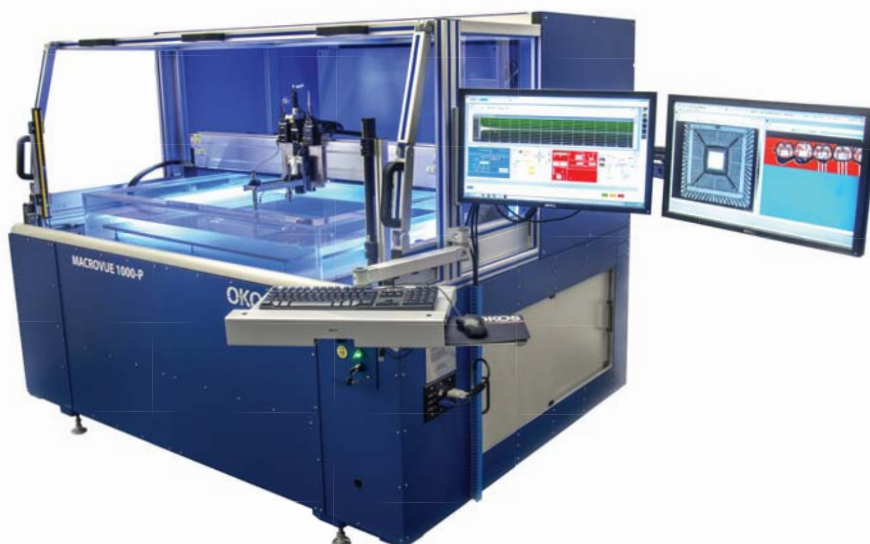
Step Envelope Up to 600 mm

Low Maintenance Focus Axis:

Focus Envelope Up to 150 mm

Tank:

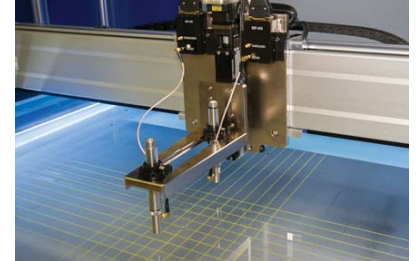
Depth Up to 500 mm



MACROVUE-P SCANNING ACOUSTIC MICROSCOPE

Included Software Modes:

- Basic (user friendly)
- Advanced (detailed analysis)
- Production (automated scanning)
- Offline Analysis (virtual scanning)



OKOS Digital Imaging System (ODIS)



MACROVUE-P imaging power surpasses modern standards delivering premium FA Lab features to semiconductor fabrication facilities. ODIS is the latest Acoustic Microscopy software with rich technical content built on current platforms and industry feedback. It includes both time domain and frequency domain imaging in real-time. Advanced analysis is provided through quantitative tools for measurement and classification of parts.

The Analysis version of ODIS allows non-scanning computers to virtually scan, view, and analyze data for simultaneous real-time analysis or post collection review. Supplied with your choice of Windows 7 or 10.

- Counterfeit Detection
- Product Inspection
- Product Reliability
- Quality Control
- Process Validation
- Failure Analysis
- Vendor Qualification
- R&D

Application Specific Transducers

for the highest quality resolution.

Multiple transducer design for enhanced scan capability.

